

In Situ Crystallization to Zinc Aluminate Films with Controlled Surface Microstructure and Anticorrosion Performance

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Spinel-type zinc aluminate (ZnAl_2O_4) thin films with controlled surface microstructure on aluminum substrates were fabricated via a facile and effective in situ crystallization method without using any templates or surfactants. The surface microstructure of ZnAl_2O_4 films could be significantly controlled by varying the experimental conditions including concentration of reactants, crystallization temperature, and crystallization time. After surface modification, the specific topography of ZnAl_2O_4 films was beneficial to obtain surface hydrophobic or superhydrophobic properties. More importantly, compared to nanoparticle- and nanowire-assembled ZnAl_2O_4 films, nanowire-assembled ZnAl_2O_4 film provided a more effective barrier to aggressive species for aluminum substrates in a wide range of pH values; very low corrosion current density of the order of $\sim 10^{-9} \text{ A cm}^{-2}$ could be achieved. A new contribution to the development of advanced coating system with ZnAl_2O_4 film materials that can be used in practical application for corrosion protection of aluminum materials is provided. © 2011 American Institute of Chemical Engineers *AIChE J.* 58: 2639–2649, 2012
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Introduction

Spinel-type AB_2O_4 complex metal oxides, as an important class of functional inorganic materials, have attracted extensive attention in past two decades, due to their excellent applications in optoelectronics,^{1–5} gas sensors,^{6,7} medicines,^{8,9} magnetic devices,^{10,11} catalyst supports,^{12–14} and catalysts.^{15–17} Recently, tremendous efforts have been directed toward the controlled growth of spinel nanostructures, which provides the flexibility for tailoring their physicochemical properties according to special applications.^{18–20} As for spinel-type oxide films, their unique surface topography can significantly affect the mechanical, optical, electrical, and biological properties of materials.^{21,22}

Zinc aluminate (ZnAl_2O_4), well-known as a wide band gap semiconductor (3.8 eV), has been widely used as dielectric materials due to its desirable properties, such as high mechanical and chemical resistance, high thermal stability, etc.^{23–25} Historically, there were a number of research works for preparing ZnAl_2O_4 fine powders by conventional solid-state route,^{26–28} chemical vapor deposition,²⁹ sol-gel technique,^{30,31} and hydrothermal method.^{32–34} However, there are few reports on the fabrication of continuous ZnAl_2O_4 films, mainly owing to the difficulty in controlling the precipitation rate of films.^{35–38} For instance, Wu et al.³⁶ prepared interconnected microstructural ZnAl_2O_4 films on silicon substrates via a sol-gel route using aluminum tri-*sec*-butoxide as the source

of Al and hexylene glycol as a solvent. Recently, Tian et al.³⁸ also synthesized mesoporous ZnAl_2O_4 films through evaporation-induced method using triblock copolymer pluronic F-127 as structure-directing agent. Moreover, rare-earth-doped ZnAl_2O_4 films could be prepared by spray pyrolysis technique.³⁷ Generally, these methods need complicated processing and/or specialized equipments. In most cases, they require handling of large amount of organic salts, toxic solvents, or surfactants, which cause expensive costs as well as environment pollution. Therefore, the above physical and chemical methods are not suitable for environmentally benign scale-up synthesis. Owing to the uncontrollable phase separation during multicomponent reactions and poor adhesion to underlying substrate, a challenge still remains to develop more effective protocols for the microstructure control of ZnAl_2O_4 films and further the performance of new applications in various fields such as advanced catalysts, gas sensors, and coating materials.

Conversely, it is known that the aluminum and aluminum alloys are highly susceptible to localized corrosion, especially in chloride-containing environments. Over the years, the development of diverse active corrosion protection systems or strategies for preventing the degradation processes of metallic substrates has been an issue of prime importance for industrial applications.^{39,40} Among them, anodization is thought to be an effective way of corrosion protection by thick oxide layer formed on substrate.⁴¹ However, because of the porous nature, the oxide layer cannot provide adequate barrier property to prevent the ingress of corrosive species onto the metal surface.⁴² Another approach of corrosion protection is achieved by deposition of organic barrier

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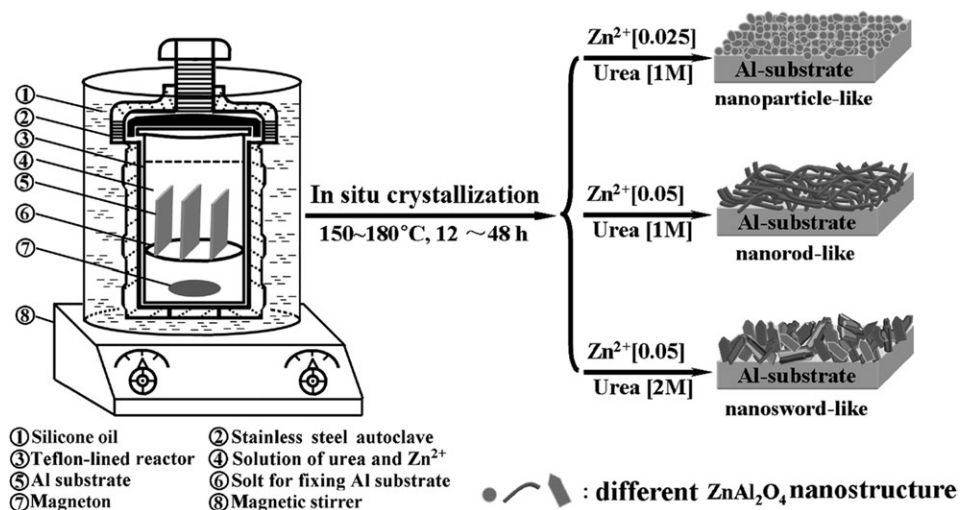


Figure 1. Schematic illustration of the formation process of $ZnAl_2O_4$ nanostructures on the aluminum substrates.

coatings on substrate, which can prevent contact of the metal with the corrosive environment.^{43,44} Usually, adhesion of organic coatings is far away from satisfactory unless special pretreatment like chromate coating is used.^{45,46} However, the carcinogenic nature of chromate coating limits its use. Therefore, the development of a new approach to introduce environmentally friendly corrosion protection coating systems with excellent performance becomes an urgent need for many industries.

In this article, we reported the first example of direct fabrication of $ZnAl_2O_4$ films using aluminum foil as both the substrate and sole aluminum source. The surface microstructure of the obtained $ZnAl_2O_4$ films can be controlled via a facile and effective *in situ* crystallization approach without using any templates or surfactants. The formation process of the nanostructure-assembled $ZnAl_2O_4$ films on aluminum substrates is schematically illustrated in Figure 1. The effects of concentration of reactants, crystallization time, and crystallization temperature on the surface morphologies of $ZnAl_2O_4$ films were investigated. More significantly, it is found that the resulting $ZnAl_2O_4$ films could adhere strongly to the substrate and provide effective corrosion-resistant coating for the underlying aluminum. To the best of our knowledge, there are no reports on *in situ* fabrication of $ZnAl_2O_4$ thin films with controlled nanostructures and resulting anticorrosion protection for aluminum substrates.

Experimental

Materials

Aluminum foils (purity: >99.99% and thickness: 0.26 mm) purchased from Beijing Jing Xi Chemical Technology were cut into square pieces with a size of 20 mm × 20 mm as Al substrates. First, Al substrates were treated in dilute HCl solution (1.0 M) for 2 min at room-temperature and rinsed with distilled water to remove the surface oxide layer. Subsequently, substrates were ultrasonically cleaned in acetone to remove the surface organic contaminations, and finally air-dried.

Fabrication of spinel-type $ZnAl_2O_4$ thin films

$ZnAl_2O_4$ thin films with different surface microstructures were fabricated by one-step *in situ* crystallization on Al substrates. In a typical procedure, $Zn(NO_3)_2 \cdot 6H_2O$ (2.0 mmol)

and urea (80 mmol) were dissolved in 80 mL of water/ethanol mixture solvent (v/v = 1/1) to form a clear solution ($[Zn^{2+}] = 0.025$ M and $[urea] = 1.0$ M). The resulting solution was transferred into 100 mL of Teflon-lined autoclave with an inner diameter of 4.0 cm, where the treated Al substrates were vertically fixed onto a slot (Figure 1). Subsequently, the autoclave was placed into an oil bath and stirred magnetically with a rate of about 200 rpm, and then heated at 180°C for 24 h. After cooling, the resulting $ZnAl_2O_4$ films were rinsed with ethanol and dried at ambient temperature. The microstructure control experiments of $ZnAl_2O_4$ films were carried out in a similar process by changing the synthesis parameters including concentration of reactants, crystallization temperature, and crystallization time (Table 1). The surface hydrophobization of as-fabricated $ZnAl_2O_4$ films was performed by immersion in 0.05 M sodium laurate aqueous solution at 70°C for 12 h. After immersion, the films were rinsed with ethanol and dried at ambient temperature.

Characterization

Powder X-ray diffraction (XRD) patterns of film samples with a size of about 5 mm × 5 mm were directly collected using a Shimadzu XRD-6000 diffractometer under the following conditions: 40 kV, 30 mA, graphite-filtered Cu K α radiation. The samples were step-scanned in steps of 0.04° (2 θ) using a count time of 10 s/step.

Field emission scanning electron microscopy (FESEM) of samples was directly carried out on a Zeiss Supra 55 instrument with an accelerating voltage of 20 kV. Before FESEM observation, films were sputtered with gold to provide a conducting surface.

Transmission electron microscopy (TEM) was taken using a JEOL-2100 transmission electron microscope operated at 100 kV. For TEM analysis, $ZnAl_2O_4$ powders scraped from the surface of films were dispersed in ethanol. A droplet of the ultrasonically dispersed powders was placed onto an amorphous carbon-coated copper grid and dried at ambient temperature. High-resolution transmission electron microscopy (HRTEM) was carried out at an accelerating voltage of 200 kV.

Room-temperature Fourier transform infrared (FTIR) spectrum was recorded in the range of 4000–400 cm^{-1} with 2 cm^{-1} resolution on a Bruker Vector-22 Fourier transform

Table 1. The Synthesis Parameters and Morphologies of As-Fabricated ZnAl₂O₄ Films on Aluminum Substrates

Samples	Zn ²⁺ (M)	Urea (M)	Crystallization Time (h)	Crystallization Temperature (°C)	Morphology
ZA-a	0.025	1	24	180	Nanoparticle
ZA-b	0.05	1	24	180	Nanorod
ZA-c	0.05	2	24	180	Nanosword
ZA-d	0.05	2	24	60	Curved nanosheet
ZA-e	0.05	2	24	150	Irregular nanosheet
ZA-f	0.025	1	12	180	Nanoparticle
ZA-g	0.05	1	12	180	Nanorod
ZA-h	0.05	2	12	180	Nanosword
ZA-i	0.025	1	48	180	Nanoparticle
ZA-j	0.05	1	48	180	Nanorod
ZA-k	0.05	2	48	180	Nanosword

spectrometer using the KBr pellet technique (1 mg of sample in 100 mg of KBr).

Atomic force microscopy (AFM) micrograph was taken on a DI nanoscope IV (Digital Instruments) using the tapping mode at a resolution of 2 nm in *X–Y* and 0.1 nm in *Z* orientation.

Static water contact angle (CA) of samples was measured on a commercial drop-shape analyses system (DSA 100, KüRSS GmbH, Germany) at ambient temperature. The equilibrium water CA was measured with a fixed needle supplying a water drop of 5 μ L, and five different points on each sample were investigated.

X-ray photoelectron spectroscopy (XPS) was performed on a VG ESCALAB MKII spectrometer with a monochromatic Al K α X-ray radiation (1486.6 eV photons). The depth profiling experiment was conducted at argon partial pressure of 10^{−6} Torr, while applying 4 kV voltage at an ion beam current of 10 mA cm², resulting in a \sim 0.5-nm/min etching rate. Binding energies were calibrated based on graphite C 1s peak at 284.6 eV.

Corrosion-resistant property evaluations

A conventional three-electrode configuration was used with the ZnAl₂O₄ films under test as the working electrode with an area of 1.0 cm², a platinum electrode as the counter electrode, and a saturated calomel electrode as the reference electrode. Aqueous sodium chloride solution (3.5%) was used as the electrolyte. The samples were immersed in the corrosive medium for 30 min before the electrochemical tests to ensure the steady state. The pH value was adjusted by adding diluted hydrochloric acid (1.0 M) and sodium hydroxide (1.0 M). The Tafel polarization tests were recorded with a CHI 660C electrochemical workstation at room-temperature at a sweep rate of 10 mV s^{−1}. The electrochemical

impedance spectroscopy (EIS) data were acquired at open circuit potential applying a 10 mV sinusoidal perturbation in the 100 kHz–10 mHz frequency range at room-temperature.

Results and Discussion

Fabrication and characterization of ZnAl₂O₄ thin films

The different types of ZnAl₂O₄ nanostructures were grown on Al substrates by varying concentrations of reactants, crystallization time, and crystallization temperature (Table 1). Figure 2a shows the XRD patterns of three representative ZnAl₂O₄ film samples (ZA-a, ZA-b, and ZA-c). The samples indicate the identical characteristic (220), (311), (422), and (511) reflections of cubic spinel-type ZnAl₂O₄ phase (JCPDS no. 05-0669), except for the reflections from Al substrates. Figure 2b depicts the FTIR spectrum of ZnAl₂O₄ powder scraped from ZA-b sample. In detail, a strong and broad absorption band centered at around 3421 cm^{−1} can be identified as the hydroxyl stretching band $\nu(\text{OH}_{\text{str}})$, arising from absorption water molecules. Another absorption band resulting from the hydroxyl deformation mode of water, $\delta(\text{H}_2\text{O})$, is recorded at around 1625 cm^{−1}. There are two strong characteristic absorption peaks at about 558 and 677 cm^{−1}, which can be assigned to the stretching vibrations of the metal–oxygen bonds for spinel structure in tetrahedral positions and octahedral positions, respectively.^{30,47} The aforementioned confirms that the obtained products on Al substrates are pure-phase ZnAl₂O₄.

The surface morphologies of ZnAl₂O₄ films were investigated by FESEM micrographs. From FESEM micrograph of ZA-a sample (Figure 3a), it can be seen that a large number of nanoparticles are closely stacked together and homogeneously distributed on the substrate surface. According to FESEM micrographs, the average particle size of ZA-a

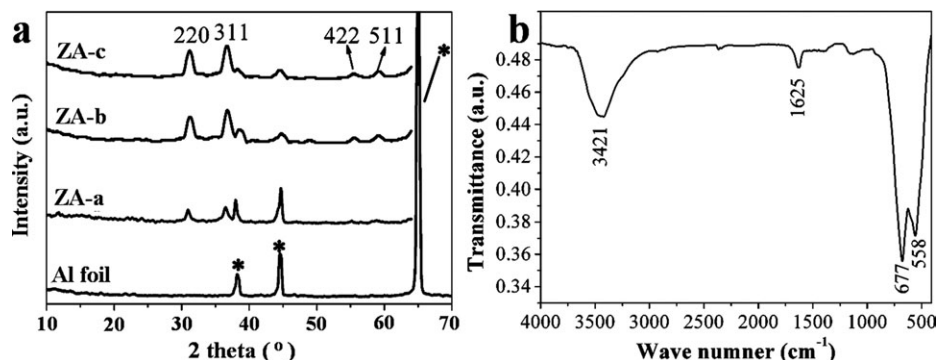


Figure 2. XRD patterns of as-fabricated ZnAl₂O₄ films (a), and * indicates the reflection peaks from the aluminum substrate; FTIR spectrum of ZA-b film sample (b).

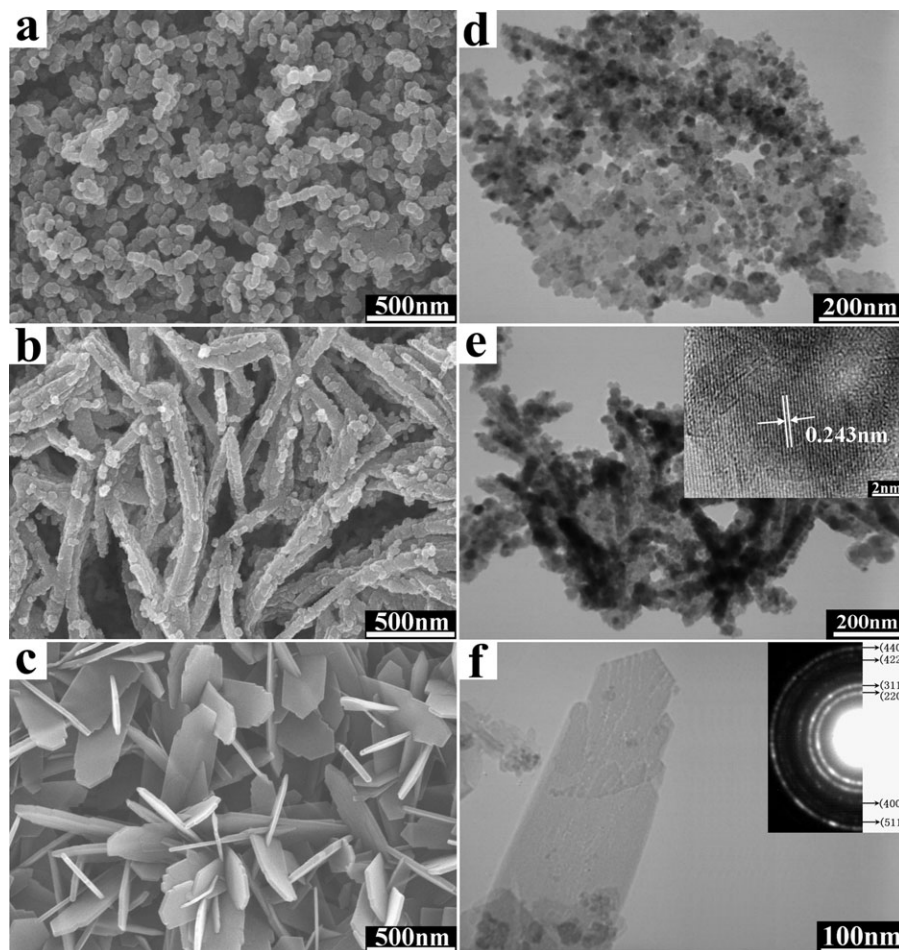


Figure 3. FESEM micrographs of ZnAl_2O_4 film samples.

ZA-a (a), ZA-b (b), and ZA-c (c); TEM micrograph of nanoparticles scraped from ZA-a (d); TEM micrograph of nanorods scraped from ZA-b (e), and inset shows HRTEM micrograph of an individual nanorods; TEM micrograph of nanoswords scraped from ZA-c (f), and inset shows the corresponding SAED image of an individual nanosword.

sample estimated from no less than 100 particles is about 38 ± 5 nm. ZA-b sample presents the morphology of nanorods with a diameter of about 50–80 nm and a length of about 1.5–3.0 μm (Figure 3b), while ZA-c sample shows the morphology of nanoswords with a lateral size of about 150–250 nm and a thickness of about 20–30 nm (Figure 3c).

The ZnAl_2O_4 nanostructures grown on Al substrates were investigated by TEM and HRTEM micrographs. As shown in Figure 3d, ZnAl_2O_4 layer in ZA-a presents the character of nanoparticles with a diameter of about 20 nm. However, as for ZA-b sample, numerous nanoparticles (10–20 nm) interconnect with each other along the rod axis to self-assemble into larger rod-like morphology (Figure 3e). Further, close inspection of representative HRTEM micrograph of an individual nanorod clearly reveals the presence of an interplanar distance of about 0.243 nm that is characteristic of (311) plane of ZnAl_2O_4 phase (inset in Figure 3e). Interestingly, ZnAl_2O_4 layer in ZA-c shows nanosword-like shape (Figure 3f). Additionally, selected area electron diffraction (SAED) pattern of an individual nanosword (inset in Figure 3f) substantiates six discernible diffraction characteristic rings corresponding to cubic ZnAl_2O_4 phase, confirming the polycrystalline nature of ZnAl_2O_4 layers.

The surface microstructure of as-fabricated ZnAl_2O_4 films was characterized by AFM images (Figure 4). Two-dimen-

sional AFM images (Figures 4a–c) reveal that distinct protrusions and pitches present on the rough surface of films. The root-mean-square roughness of the films is estimated to be 51, 144, and 263 nm for ZA-a, ZA-b, and ZA-c, respectively, well in agreement with the change in the surface pattern from nanoparticles to nanorods and nanoswords. Moreover, small bulges in ZA-a, ravines in ZA-b, and isolated triangular islands in ZA-c can be resolved in the three-dimensional AFM images (Figures 4d–f). The bulges and ravines result from the close adherence and assembly of numerous nanoparticles and nanorods, respectively, while the isolated triangular islands are attributed to the vertex of some perpendicular nanoswords. In light of the particular surface topography of the as-fabricated ZnAl_2O_4 films, it can, therefore, be expected to design hydrophobic surfaces. It can be observed that when a water droplet is dropped onto ZnAl_2O_4 film on substrate, it spreads very quickly over the surface with low water CA of about 8° (Figure 5a), indicating the surface hydrophilicity of this film due to “high-energy interface” for metal oxide. Nevertheless, when the surface of ZnAl_2O_4 films is modified by simple immersion in an aqueous solution of sodium laurate, the water CA increases gradually from $139 \pm 2^\circ$ for ZA-a to $145 \pm 2^\circ$ for ZA-b, and $153 \pm 2^\circ$ for ZA-c (Figures 5b–d), indicative of high surface hydrophobicity for ZA-a and ZA-b, and even

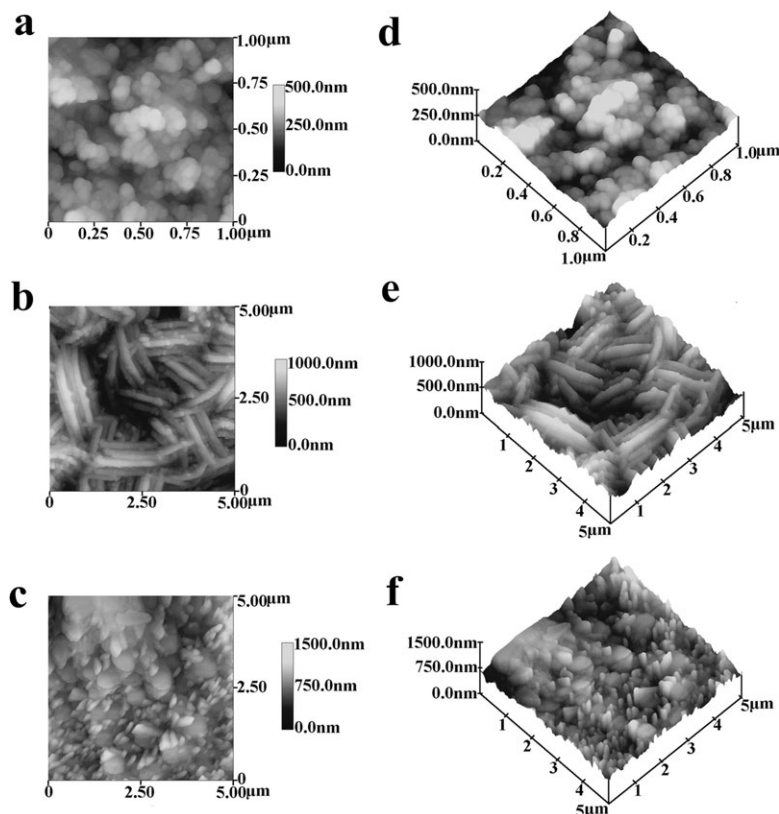


Figure 4. Two-dimensional AFM images of ZnAl_2O_4 films.

ZA-a (a), ZA-b (b), and ZA-c (c); three-dimensional AFM images of ZnAl_2O_4 films: ZA-a (d), ZA-b (e), and ZA-c (f).

surface superhydrophobicity for ZA-c with the water CA higher than 150° . The enhanced hydrophobic properties can be mainly ascribed to the increasing surface roughness of ZnAl_2O_4 films.^{48–50}

XPS measurements within a binding energies range of 0–1200 eV were performed to investigate the surface/near-surface chemical states and the thickness of the ZnAl_2O_4 layers on Al substrates. The representative XPS result of ZA-b sample is shown in Figure 6. It is observed from the inset of Figure 6a that there are two photoemission peaks centered at about 1021.5 and 1044.7 eV, which are attributed to Zn $2p_{3/2}$ and Zn $2p_{1/2}$ of surface ZnAl_2O_4 layers, respectively. The depth profile analysis by Ar^+ sputtering collected across the film reveals an obvious distribution gradient of the Zn concentration, which gives a film thickness of about 270 nm for ZA-b. In particular, the Zn/(Zn + Al + O) molar ratios of about 14% at the outermost surface of ZnAl_2O_4 film match well with the nominal molar ratio of spinel phase. In the three-dimensional Al 2p XPS spectra, based on different Ar^+ sputtering time (Figure 6b), a small peak at 75.6 eV resulting from the tetrahedral coordination of amorphous Al_2O_3 can be detected at the uppermost surface of Al substrate,⁵¹ while the main peak centered at 74.0 eV is associated with the octahedral coordination of aluminum species.³⁵ The presence of continuous ultrathin ZnAl_2O_4 layers of smaller than 300 nm in thickness implies that the *in situ* growth of ZnAl_2O_4 only occurs in the surface regions of the substrate and is diffusion-limited.

Formation mechanism of ZnAl_2O_4 thin films

In the present system, to avoid the effect of the gradients of temperature and concentration of reaction system on the growth of ZnAl_2O_4 thin films, the magnetic stirring with a rate of about 200 rpm was applied. In addition, it is well-known that the operating pressure in solvothermal reaction is related to the compactness of the autoclave and reaction temperature. Because of the fixed compactness of 80% in our case, only the operating pressure changed with the reaction temperature. Assuming that the vaporization enthalpies of water and ethanol vary slightly with temperature and the solvents in the autoclave are considered as ideal liquids, the operating pressures for the present synthesis system estimated by the Clausius–Clapeyron equation and Raoult's law are about 0.9 MPa for 150°C and 1.5 MPa for 180°C , respectively.^{52,53}

To clearly understand the growth process of ZnAl_2O_4 film, the crystallization temperature was varied (Table 1). Typically, to take the preparation of ZnAl_2O_4 films using 0.05 M Zn^{2+} and 2 M urea as an example, numerous irregular curved nanosheets with the thickness of about 10–20 nm are randomly grown on the surface of the substrate at the low crystallization temperature of 60°C (Figure 7a). When the crystallization temperature reaches 150°C , the resulting film is composed of a large number of nanosheets with irregular edges and coarse surfaces and some nanoparticles (Figure 7b), as a result of fast growth of ZnAl_2O_4 crystals at high-temperature on the basis of the kinetics and

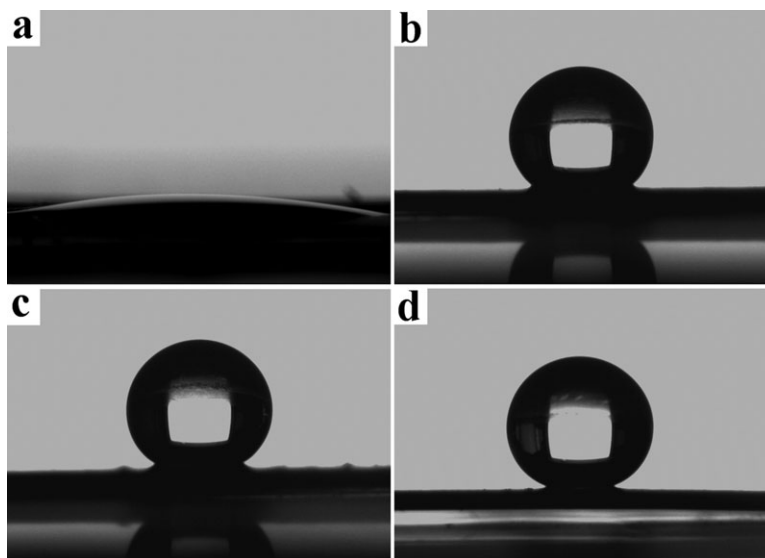
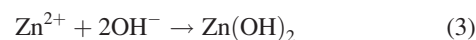


Figure 5. Shapes of water droplets over the surface of the as-fabricated ZnAl_2O_4 films (a), hydrophobic ZA-a (b), hydrophobic ZA-b (c), and hydrophobic ZA-c (d), revealing a CA of about 8° , 139° , 145° , and 153° , respectively.

thermodynamics of crystal growth. Further increasing the temperature to 180°C , sword-like nanosheets with almost parallel edges and smooth surface are formed on the substrate surface (Figure 7c). In addition, the increase in the stacking thickness of nanosheets with the crystallization temperature can be observed.

Besides, the effect of the crystallization time on the growth of ZnAl_2O_4 nanostructures on substrates was investigated (Table 1). It is found that with increasing the crystallization time from 12 to 48 h, there is no significant difference in the morphologies of ZnAl_2O_4 films in each case, but the crystal size and regularity of particle-like, rod-like, and sword-like ZnAl_2O_4 nanostructures can be improved gradually (Figures 7d–i), which is attributed to the growth–dissolution–reorganization process (Ostwald ripening) of ZnAl_2O_4 crystallites.⁵⁴

In tandem with the above experimental observations, one possible growth mechanism for the ZnAl_2O_4 films is proposed. The chemical reactions involved were believed to proceed as follows (Eqs. 1–4)



At the beginning of the growth, urea hydrolyzes to give NH_4^+ , CO_2 , and OH^- with the increase of pH value at the elevated reaction temperatures (Eq. 1). It is well-known that aluminum in air or under humid conditions can be oxidized by oxygen and the reaction is very slow due to the formation of an oxide passivation layer on the surface. However, the oxidation may be accelerated intensely in the presence of alkali solution, and, thus, Al^{3+} can quickly enter the solution in the form of $[\text{Al}(\text{OH})_4]^-$ complex. In our case, because of the high OH^- concentration in the solution and the presence of dissolved oxygen, Al^{3+} ions can be released continuously into the reaction system in the form of $[\text{Al}(\text{OH})_4]^-$ complex by chemical etching of aluminum substrate under solvothermal conditions

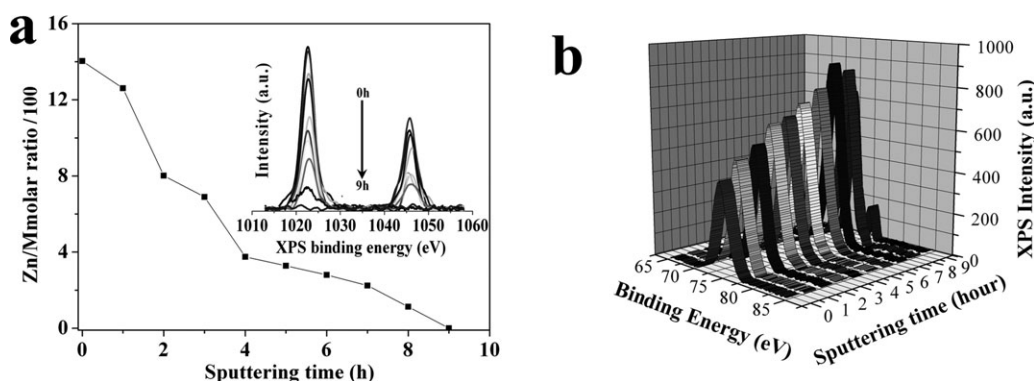


Figure 6. The molar ratio of Zn/M ($M = \text{Zn} + \text{Al} + \text{O}$) of ZA-b (a) as a function of film depth expressed in terms of sputtering time, and inset is the corresponding depth profile of the Zn 2p spectra with *in situ* Ar^+ sputtering at different times.

Three-dimensional depth profile of Al 2p XPS spectra of ZA-b (b) at different Ar^+ sputtering time.

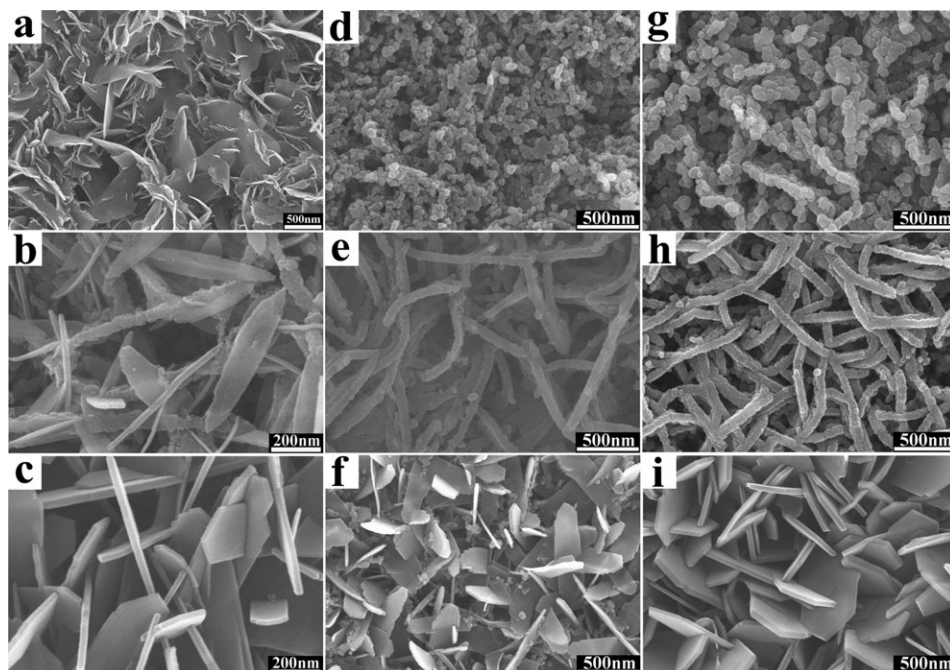


Figure 7. FESEM micrographs of ZnAl_2O_4 films fabricated under different experimental conditions.

ZA-d (a), ZA-e (b), ZA-c (c), ZA-f (d), ZA-g (e), ZA-h (f), ZA-i (g), ZA-j (h), and ZA-k (i).

(Eq. 2), while Zn^{2+} cations immediately react with OH^- to form $\text{Zn}(\text{OH})_2$ (Eq. 3). Subsequently, ZnAl_2O_4 nuclei are formed through the structural transformation of $\text{Zn}(\text{OH})_2$ and $\text{Al}(\text{OH})_4^-$ intermediates generated in the solution (Eq. 4) and deposited on the substrate surface as the growth centers for crystallization.^{55,56} The mixture solvent of ethanol and water can prevent the aluminum substrate from collapsing and, thus, activates the surfaces of the substrate to certain extent, which is further supported by the fact that no ZnAl_2O_4 film is formed with the addition of sodium hydroxide instead of urea under hydrothermal conditions in the absence of ethanol. Finally, the fusion of adjacent ZnAl_2O_4 crystals along the crystal plane with the lowest lattice-free energy and the growth of ZnAl_2O_4 crystals construct ZnAl_2O_4 films with different surface patterns.^{57,58} According to the above Eqs. 1–4, the higher crystallization temperature can accelerate hydrolysis of urea under the solvothermal conditions, thus, leading to the increase in the concentration of OH^- ions in the solution and the etching rate of aluminum from the substrate. Meanwhile, the higher initial urea and Zn^{2+} concentrations would be advantageous for the formation of ZnAl_2O_4 films with high integrality of surface patterns.⁵⁹ Therefore, the prevailing growth morphology of the ZnAl_2O_4 architectures is strongly influenced by the degree of supersaturation under solvothermal condition, which is mainly determined by the urea and Zn^{2+} concentrations and the crystallization temperature. Certainly, during the long growth time, crystallization goes on at the substrate surfaces so long as an initial morphology of ZnAl_2O_4 nanostructure is maintained.

As a result, *in situ* crystallization yields high-quality ZnAl_2O_4 nanostructures with high purity on the substrates. Although the exact formation mechanism for the different ZnAl_2O_4 architectures on substrate still remains elusive, the higher free energy of initial crystalline ZnAl_2O_4 nanoparticles is believed to drive the crystal growth of resulting

nanorod-like and nanosword-like ZnAl_2O_4 architectures. The self-assembly fabrication of ZnAl_2O_4 nanostructures from small nanoparticles is driven by a reduction of surface energy. The directed growth is limited by the stability of the nanostructures, and, thus, the size and shape of the resulting ZnAl_2O_4 nanorods and nanoswords are relatively uniform. In addition, compared to other ZnAl_2O_4 films reported in the literature,^{35–38} as-fabricated ZnAl_2O_4 films prepared by the present method show more multifarious and excellent surface nanostructures, which can lead to the enhanced efficiency in the physicochemical performance.

Anticorrosion performance of ZnAl_2O_4 thin films

The anticorrosion performance of as-fabricated ZnAl_2O_4 films for the underlying aluminum is investigated by linear polarization measurements in a corrosive environment of neutral 3.5% aqueous sodium chloride solution at room-temperature, where chloride ions are known as an aggressive pitting corrosion species. In a typical Tafel polarization curve, the values of voltage and current density at the intersection of Tafel slopes are known as the corrosion potential and the corrosion current. The corrosion current density (corrosion current per area unit) is directly proportional to the corrosion rate. Therefore, the lower corrosion current density corresponds to the lower corrosion rate and, thus, better corrosion resistance. As shown in Figure 8a, in the passive region of polarization curves, ZA-a and ZA-b samples exhibit about three orders of magnitude reduction in polarization current as low as about $10^{-9} \text{ A cm}^{-2}$, compared to the bare Al substrate, indicative of significant corrosion resistance of aluminum. Such low current densities have been infrequently observed previously for pristine metal oxide coating materials or their powder counterparts.⁶⁰ A slightly increased polarization current, however, occurs for ZA-c sample. Moreover, the open circuit potential of ZA-b sample is found

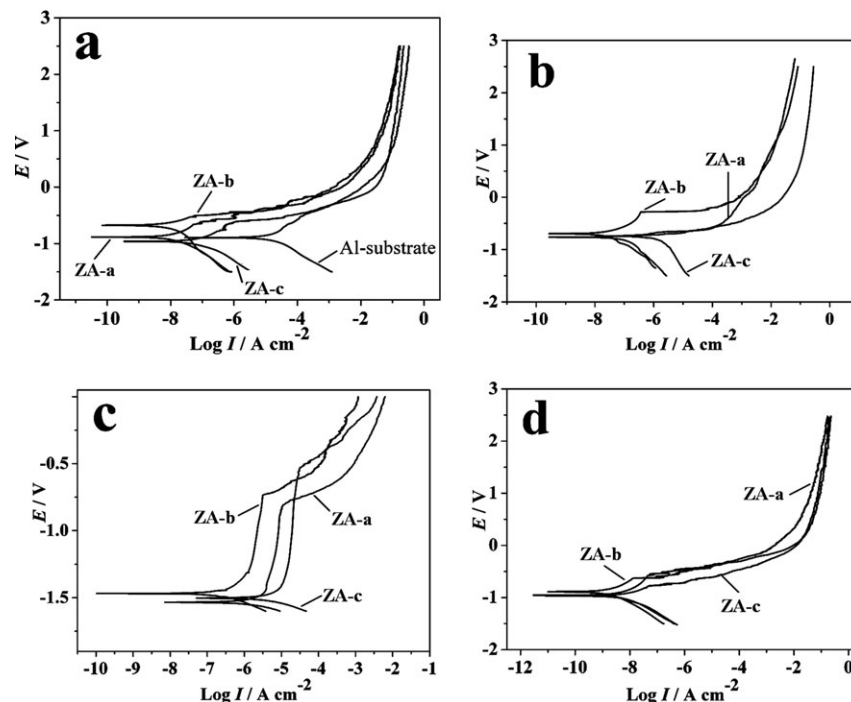


Figure 8. Polarization curves of samples immersed in neutral 3.5% aqueous sodium chloride solution (a), immersed in acidic solutions (b), immersed in basic solutions (c), and immersed in neutral 3.5% aqueous sodium chloride solution after surface hydrophobization (d).

to be less changed after being immersed in the corrosive medium for 30 days. The above results confirm the significant corrosion-resistant properties of as-fabricated ZnAl_2O_4 films due to the formation of passive layer. Compared with those in neutral 3.5% aqueous sodium chloride solution, the polarization currents of ZnAl_2O_4 films are basically unchanged in acidic solutions (pH = 2; Figure 8b), and less than 10^{-7} A cm⁻² in basic solutions (pH = 12; Figure 8c). Furthermore, after surface hydrophobization treatment with sodium laurate, the polarization measurements of ZnAl_2O_4 films reveal that the hydrophobic ZnAl_2O_4 films give lower current densities below 10^{-9} A cm⁻² (Figure 8d), compared to the hydrophilic ZnAl_2O_4 films. It suggests that the hydrophobic ZnAl_2O_4 films provide more effective corrosion-resistant coating, which originates from the superior barrier ability to corrosive ion migration.

EIS measurements are also used to better characterize the protective behavior of the ZnAl_2O_4 films. The Nyquist plots

of ZA-a, ZA-b, ZA-c, and bare Al substrate subject to neutral 3.5% aqueous sodium chloride solution are shown in Figure 9a. It can be seen that the impedance spectrum of as-fabricated samples consist of two semicircles and a sloping line. The electrochemical impedance of ZnAl_2O_4 films is approximately two orders of magnitude larger than that of bare Al substrate. Especially, compared to ZA-a and ZA-c samples, ZA-b sample exhibits higher electrochemical impedance, indicating that ZA-b has larger charge resistance to ion migration. Figure 9b shows the typical Bode plot of ZA-b sample. The high-frequency time-dependent component at about 10^4 Hz is related to Faradic charge-transfer process of the surface ZnAl_2O_4 layer extending from the dense intermediate oxide barrier layer to the outermost surface of the film, and the time component at about 1 Hz originates from the capacitance of the intermediate oxide barrier layer adjoining the metal film. The low-frequency time-dependent component at 0.01 Hz (Warburg impedance) originates from the

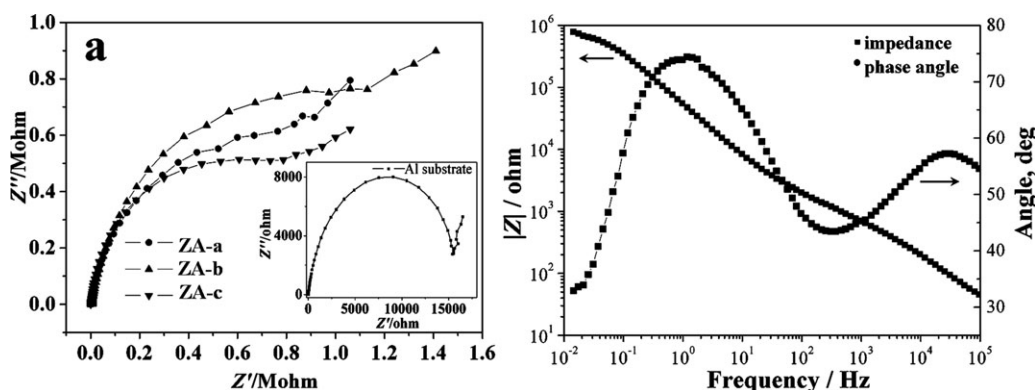


Figure 9. Nyquist plots (a) of samples immersed in neutral 3.5% aqueous sodium chloride solution, and typical Bode plot (b) of ZA-b sample.

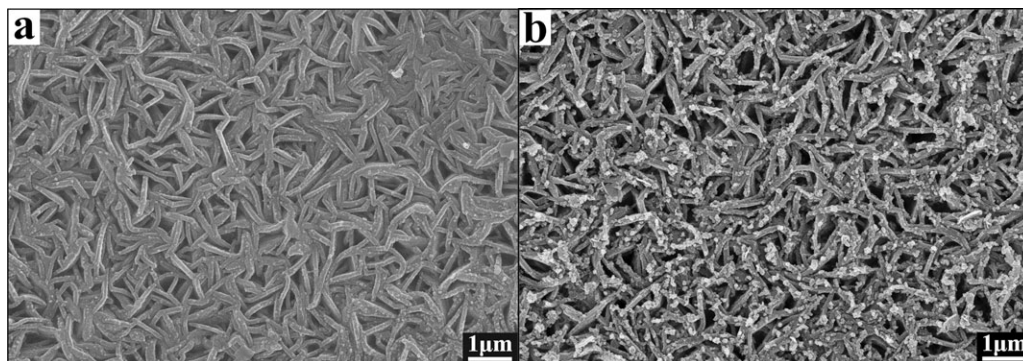


Figure 10. FESEM micrographs of ZA-b sample: before (a) and after (b) immersion in 3.5% aqueous sodium chloride solution for 30 days.

diffusion of corrosive reactants or species produced by corrosion through a passive layer with a high charge-transfer resistance.^{61,62}

It is well-known that high adhesion of the anticorrosion coating to the metal substrate is essential for practical applications. FESEM micrographs of ZA-b sample show the unchanged surface microstructure after long-term immersion in 3.5% aqueous sodium chloride solution for 30 days (Figure 10). Meanwhile, after cross-cutting through the surface of ZA-b film, no significant peeling or delamination is observed (Figure 11). The above result confirms excellent chemical stability and strong adhesion of as-fabricated ZnAl_2O_4 film, which is attributed to direct growth of ZnAl_2O_4 crystallites from substrate.

In general, ZA-b sample shows the highest anticorrosion ability, and the order of corrosion-resistant ability obtained is $\text{ZA-b} > \text{ZA-a} > \text{ZA-c}$. It is well-known that the rate of corrosion and the diffusion of chloride ions are determined by the size of pore pathways. In the present system, a dense surface structure for compact nanorod-assembled ZnAl_2O_4 film with few pores can provide good resistance to the transportation of ions and electrons, thus, resulting in superior corrosion-resistant ability for the underlying aluminum substrate. A more accessible porous structure for ZA-a (nanoparticle assembled) and ZA-c (nanosword assembled), however, may allow the electrolyte to penetrate toward the metal surface and, thus, initiate the corrosion processes more easily.

Conclusions

ZnAl_2O_4 thin films with controlled surface microstructure have been successfully fabricated on aluminum substrates by

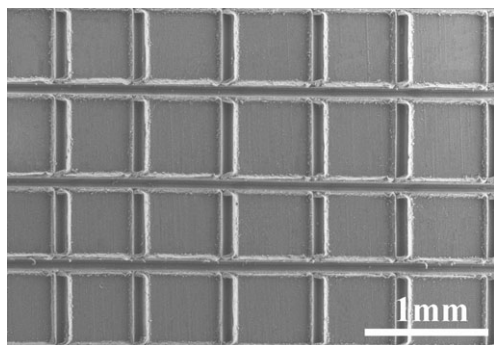


Figure 11. FESEM micrograph of ZA-b sample tested for adhesion.

a simple one-step *in situ* crystallization approach. The growth of ZnAl_2O_4 nanostructures including nanoparticles, nanorods, and nanoswords was found to be greatly affected by the concentration of Zn^{2+} and urea under the solvothermal conditions. Polarization measurements revealed that the nanorod-assembled ZnAl_2O_4 film with strong adhesion to the aluminum substrate could effectively protect the aluminum from corrosion in a wide range of pH values, and that very low corrosion current densities of the order of $\sim 10^{-9} \text{ A cm}^{-2}$ could be achieved. EIS results showed that the ZnAl_2O_4 film could serve as a passive layer with a high charge-transfer resistance contributing to its anticorrosion ability. Based on these properties of the as-fabricated ZnAl_2O_4 film as well as nontoxic nature, it is expected that the ZnAl_2O_4 film has the potential to become an environmentally friendly alternative for increasingly regulated chromate coatings.

Acknowledgments

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